

## INFORMATION DISCLOSURE STATEMENT

Applicant : Todd et al.  
App. No. : 10/074,564  
Filed : February 11, 2002  
For : THIN FILMS AND METHODS OF  
MAKING THEM  
Examiner : Brook Kebede  
Group Art Unit : 2823

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing references that are also enclosed.


This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 8/19/03

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FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMEX.333A	APPLICATION NO. 10/074,564
 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Todd et al.	
		FILING DATE February 11, 2002	GROUP 2823

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
1.		5,214,002	05/25/93	Hayashi et al.			
2.		5,356,821	10/18/94	Naruse et al.			
3.		5,471,330	11/28/95	Sarma			
4.		6,103,600	08/15/00	Ueda et al.			

FOREIGN PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
5.		11317530	16-11-99	Japan (abstract)			X	
6.		EP 0368651 A2	16-05-90					
7.		EP 0486047 A2	20-05-92					
8.		EP 0747974 A2	11-12-96					
9.		EP 1065728 A2	03-01-01					
10.		GB 2332564 A	23-06-99	United Kingdom				

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
11.	Olivares, J. et al.; "Solid-phase crystallization of amorphous SiGe films deposited by LPCVD on SiO <sub>2</sub> and glass," Thin Solid Films 337 (1999) pp. 51-54.	

S:\DOCS\JOM\JOM-5151.DOC:081903

EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	